

# Christian A Zorman

## List of Publications by Year in Descending Order

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The third column is the impact factor (IF) of the journal, and the fourth column is the number of citations of the article.

168  
papers

4,901  
citations

34  
h-index

66  
g-index

183  
ext. papers

5,524  
ext. citations

3.9  
avg, IF

5.44  
L-index

#	Paper	IF	Citations
168	Engineering the surface morphology of inkjet printed Ag by controlling solvent evaporation during plasma conversion of AgNO <sub>3</sub> inks. <i>Journal of Materials Chemistry C</i> , <b>2022</b> , 10, 5257-5265	7.1	2
167	An Absorbent, Flexible, Transparent, and Scalable Substrate for Wound Dressings. <i>IEEE Journal of Translational Engineering in Health and Medicine</i> , <b>2022</b> , 1-1	3	
166	Wireless Monitoring of Vascular Pressure Using CB-PDMS Based Flexible Strain Sensor. <i>Annual International Conference of the IEEE Engineering in Medicine and Biology Society IEEE Engineering in Medicine and Biology Society Annual International Conference</i> , <b>2021</b> , 2021, 7011-7015	0.9	
165	Plasmas for additive manufacturing. <i>Plasma Processes and Polymers</i> , <b>2020</b> , 17, 2000009	3.4	15
164	Review Inkjet Printing of Metal Structures for Electrochemical Sensor Applications. <i>Journal of the Electrochemical Society</i> , <b>2020</b> , 167, 037571	3.9	32
163	An improved tactile sensing device for material characterization via friction-induced vibrations. <i>Sensors and Actuators A: Physical</i> , <b>2020</b> , 303, 111824	3.9	
162	Non-hermetic packaging of biomedical microsystems from a materials perspective: A review. <i>Medical Devices &amp; Sensors</i> , <b>2020</b> , 3, e10082	1.6	9
161	Inkjet-Printed Hydrogen Peroxide Sensor With Sensitivity Enhanced by Plasma Activated Inorganic Metal Salt Inks. <i>Journal of Microelectromechanical Systems</i> , <b>2020</b> , 29, 1026-1031	2.5	4
160	Determination of Elastic Modulus of Silicon Carbide (SiC) Thin Diaphragms via Mode-Dependent Duffing Nonlinear Resonances. <i>Journal of Microelectromechanical Systems</i> , <b>2020</b> , 29, 783-789	2.5	2
159	Vascular Pressure-Flow Measurement Using CB-PDMS Flexible Strain Sensor. <i>IEEE Transactions on Biomedical Circuits and Systems</i> , <b>2019</b> , 13, 1451-1461	5.1	14
158	Fabrication of a Silver-Based Thermistor on Flexible, Temperature-Sensitive Substrates Using a Low-Temperature Inkjet Printing Technique <b>2019</b> , 3,		7
157	A New Class of Low-Temperature Plasma-Activated, Inorganic Salt-Based Particle-Free Inks for Inkjet Printing Metals. <i>Advanced Materials Technologies</i> , <b>2019</b> , 4, 1900119	6.8	17
156	Probing heavy ion radiation effects in silicon carbide (SiC) via 3D integrated multimode vibrating diaphragms. <i>Applied Physics Letters</i> , <b>2019</b> , 114, 101901	3.4	4
155	Wearable sensors for monitoring the physiological and biochemical profile of the athlete. <i>Npj Digital Medicine</i> , <b>2019</b> , 2, 72	15.7	128
154	Wearable sensors for monitoring the internal and external workload of the athlete. <i>Npj Digital Medicine</i> , <b>2019</b> , 2, 71	15.7	75
153	Electrically Conductive, Reduced Graphene Oxide Structures Fabricated by Inkjet Printing and Low Temperature Plasma Reduction.. <i>Advanced Materials Technologies</i> , <b>2019</b> , 4, 1900834	6.8	13
152	Nanoparticle based simple electrochemical biosensor platform for profiling of protein-nucleic acid interactions. <i>Talanta</i> , <b>2019</b> , 195, 46-54	6.2	11

151	A Programmable Sustaining Amplifier for Flexible Multimode MEMS-Referenced Oscillators. <i>IEEE Transactions on Circuits and Systems I: Regular Papers</i> , <b>2019</b> , 66, 1405-1418	3.9	4
150	Free-Standing $\Gamma$ -Ga <sub>2</sub> O <sub>3</sub> Thin Diaphragms. <i>Journal of Electronic Materials</i> , <b>2018</b> , 47, 973-981	1.9	3
149	$\beta$ -Ga <sub>2</sub> O <sub>3</sub> NEMS Oscillator for Real-Time Middle Ultraviolet (MUV) Light Detection. <i>IEEE Electron Device Letters</i> , <b>2018</b> , 39, 1230-1233	4.4	7
148	Tunable resistivity in ink-jet printed electrical structures on paper by plasma conversion of particle-free, stabilizer-free silver inks. <i>Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films</i> , <b>2018</b> , 36, 051302	2.9	8
147	Vascular Graft Pressure-Flow Monitoring Using 3D Printed MWCNT-PDMS Strain Sensors. <i>Annual International Conference of the IEEE Engineering in Medicine and Biology Society IEEE Engineering in Medicine and Biology Society Annual International Conference</i> , <b>2018</b> , 2018, 2989-2992	0.9	6
146	Direct, Transfer-Free Growth of Large-Area Hexagonal Boron Nitride Films by Plasma-Enhanced Chemical Film Conversion (PECFC) of Printable, Solution-Processed Ammonia Borane. <i>ACS Applied Materials &amp; Interfaces</i> , <b>2018</b> , 10, 43936-43945	9.5	6
145	Synthesis and characterization of Ga <sub>2</sub> O <sub>3</sub> nanosheets on 3C-SiC-on-Si by low pressure chemical vapor deposition. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , <b>2017</b> , 35, 011208	1.3	8
144	Wide bandgap $\Gamma$ -Ga <sub>2</sub> O <sub>3</sub> nanomechanical resonators for detection of middle-ultraviolet (MUV) photon radiation <b>2017</b> ,		1
143	Microplasma-Induced in Situ Formation of Patterned, Stretchable Electrical Conductors. <i>ACS Macro Letters</i> , <b>2017</b> , 6, 194-199	6.6	13
142	3C-SiC microdisk mechanical resonators with multimode resonances at radio frequencies. <i>Journal of Micromechanics and Microengineering</i> , <b>2017</b> , 27, 074001	2	3
141	Tuning Optical Signatures of Single- and Few-Layer MoS <sub>2</sub> by Blown-Bubble Bulge Straining up to Fracture. <i>Nano Letters</i> , <b>2017</b> , 17, 4568-4575	11.5	45
140	Correlating charge fluence with nanoparticle formation during in situ plasma synthesis of nanocomposite films. <i>Plasma Processes and Polymers</i> , <b>2017</b> , 14, 1700079	3.4	2
139	Materials Aspects of Micro- and Nanoelectromechanical Systems. <i>Springer Handbooks</i> , <b>2017</b> , 163-190	1.3	4
138	Ultrawide Band Gap $\Gamma$ -GaO Nanomechanical Resonators with Spatially Visualized Multimode Motion. <i>ACS Applied Materials &amp; Interfaces</i> , <b>2017</b> , 9, 43090-43097	9.5	23
137	Energetic ion radiation effects on a silicon carbide (SiC) multimode resonating diaphragm <b>2017</b> ,		2
136	Demonstration of a Packaged Capacitive Pressure Sensor System Suitable for Jet Turbofan Engine Health Monitoring <b>2016</b> ,		1
135	Synthesis of Wide Bandgap $\Gamma$ -Ga <sub>2</sub> O <sub>3</sub> Rods on 3C-SiC-on-Si. <i>Crystal Growth and Design</i> , <b>2016</b> , 16, 511-517	3.5	24
134	Atmospheric-Pressure Plasma Reduction of Metal Cation-Containing Polymer Films to Produce Electrically Conductive Nanocomposites by an Electrodiffusion Mechanism. <i>Plasma Chemistry and Plasma Processing</i> , <b>2016</b> , 36, 295-307	3.6	18

133	Packaged capacitive pressure sensor system for aircraft engine health monitoring <b>2016</b> ,		1
132	Wireless Bladder Pressure Monitor for Closed-Loop Bladder Neuromodulation. <i>Proceedings of IEEE Sensors</i> , <b>2016</b> , 2016,	0	6
131	Electrical interfaces for recording, stimulation, and sensing <b>2015</b> , 13-38		2
130	High frequency torsional-mode nanomechanical resonators enabled by very thin nanocrystalline diamond diaphragms. <i>Diamond and Related Materials</i> , <b>2015</b> , 54, 19-25	3.5	4
129	Development of an integrated surface stimulation device for systematic evaluation of wound electrotherapy. <i>Annals of Biomedical Engineering</i> , <b>2015</b> , 43, 306-13	4.7	3
128	Wireless capacitive pressure sensor operating up to 400°C from 0 to 100 psi utilizing power scavenging <b>2014</b> ,		2
127	Fabrication of electrically conductive metal patterns at the surface of polymer films by microplasma-based direct writing. <i>ACS Applied Materials &amp; Interfaces</i> , <b>2014</b> , 6, 3099-104	9.5	36
126	Microscale Characterization of a Mechanically Adaptive Polymer Nanocomposite With Cotton-Derived Cellulose Nanocrystals for Implantable BioMEMS. <i>Journal of Microelectromechanical Systems</i> , <b>2014</b> , 23, 774-784	2.5	8
125	Transfer printing of self-folding polymer-metal bilayer particles. <i>ACS Applied Materials &amp; Interfaces</i> , <b>2014</b> , 6, 22695-700	9.5	12
124	Doped polycrystalline 3C-SiC films with low stress for MEMS: part II. Characterization using micromachined structures. <i>Journal of Micromechanics and Microengineering</i> , <b>2014</b> , 24, 065001	2	1
123	Doped polycrystalline 3C-BiC films with low stress for MEMS: part I. Deposition conditions and film properties. <i>Journal of Micromechanics and Microengineering</i> , <b>2014</b> , 24, 035013	2	1
122	Contactless radio frequency probes for high-temperature characterisation of microwave integrated circuits. <i>Electronics Letters</i> , <b>2014</b> , 50, 817-819	1.1	
121	Development of polynorbornene as a structural material for microfluidics and flexible BioMEMS. <i>Journal of Applied Polymer Science</i> , <b>2014</b> , 131, n/a-n/a	2.9	3
120	Polytype control of spin qubits in silicon carbide. <i>Nature Communications</i> , <b>2013</b> , 4, 1819	17.4	229
119	A polycrystalline SiC-on-Si architecture for capacitive pressure sensing applications beyond 400 °C: Process development and device performance. <i>Journal of Materials Research</i> , <b>2013</b> , 28, 120-128	2.5	3
118	Environmentally-controlled microtensile testing of mechanically-adaptive polymer nanocomposites for ex vivo characterization. <i>Journal of Visualized Experiments</i> , <b>2013</b> , e50078	1.6	5
117	Diaphragm-based microsystems using thin film silicon carbide <b>2012</b> ,		1
116	Pressure dependence of thin polycrystalline silicon carbide diaphragm resonators <b>2012</b> ,		2

115	Adhesion and Moisture Barrier Characteristics of Roller-Cast Polydimethylsiloxane Encapsulants for Implantable Microsystems. <i>Proceedings of IEEE Sensors, 2012</i> , 2012, 1-4	0	8
114	Mechanically adaptive nanocomposites for neural interfacing. <i>MRS Bulletin, 2012</i> , 37, 581-589	3.2	75
113	Silicon Carbide BioMEMS <b>2012</b> , 351-376		
112	Amorphous Silicon Carbide as a Non-Biofouling Structural Material for Biomedical Microdevices. <i>Materials Science Forum, 2012</i> , 717-720, 537-540	0.4	5
111	Focused Ion-Beam (FIB) Nanomachining of Silicon Carbide (SiC) Stencil Masks for Nanoscale Patterning. <i>Materials Science Forum, 2012</i> , 717-720, 889-892	0.4	2
110	Amorphous Silicon Carbide (SiC) Thin Square Membranes for Resonant Micromechanical Devices. <i>Materials Science Forum, 2012</i> , 717-720, 533-536	0.4	5
109	A low-cost automated streaming potential measurement system. <i>Journal of the Association for Laboratory Automation, 2012</i> , 17, 125-33		1
108	. <i>Journal of Microelectromechanical Systems, 2011</i> , 20, 867-875	2.5	25
107	The influence of impurities and planar defects on the infrared properties of silicon carbide films. <i>Applied Physics Letters, 2011</i> , 98, 191904	3.4	10
106	Temperature dependence of SiC thin film metal-insulator-metal (MIM) capacitors on alumina over a temperature range from 25 to 500°C <b>2011</b> ,		2
105	Additive Processes for Semiconductors and Dielectric Materials. <i>MEMS Reference Shelf, 2011</i> , 37-136		3
104	Fabrication and Characterization of MEMS-Based Structures from a Bio-Inspired, Chemo-Responsive Polymer Nanocomposite. <i>Materials Research Society Symposia Proceedings, 2011</i> , 1299, 1		1
103	Removal of endotoxin from deionized water using micromachined silicon nanopore membranes. <i>Journal of Micromechanics and Microengineering, 2011</i> , 21, 054029	2	5
102	Basal lamina secreted by MDCK cells has size- and charge-selective properties. <i>American Journal of Physiology - Renal Physiology, 2011</i> , 300, F86-90	4.3	14
101	Low Stress Polycrystalline SiC Thin Films Suitable for MEMS Applications. <i>Journal of the Electrochemical Society, 2011</i> , 158, H675	3.9	14
100	A system to measure minute hydraulic permeability of nanometer scale devices in a non-destructive manner. <i>Measurement Science and Technology, 2011</i> , 22, 045802	2	3
99	Material Aspects of Micro- and Nanoelectromechanical Systems <b>2010</b> , 333-356		
98	Polycrystalline Diamond-on-Polymer Electrode Arrays Fabricated Using a Polymer-Based Transfer Process. <i>Electrochemical and Solid-State Letters, 2010</i> , 13, J129		6

97	PVD silicon carbide as a thin film packaging technology for antennas on LCP substrates for harsh environments <b>2010</b> ,		3
96	Molecular conformation and filtration properties of anionic Ficoll. <i>American Journal of Physiology - Renal Physiology</i> , <b>2010</b> , 299, F752-7	4.3	16
95	Low voltage nanoelectromechanical switches based on silicon carbide nanowires. <i>Nano Letters</i> , <b>2010</b> , 10, 2891-6	11.5	133
94	Silicon carbide MEMS-resonator-based oscillator. <i>Journal of Micromechanics and Microengineering</i> , <b>2009</b> , 19, 115027	2	17
93	Grain size control of (111) polycrystalline 3C-SiC films by doping used as folded-beam MEMS resonators for energy dissipation. <i>Microsystem Technologies</i> , <b>2009</b> , 15, 875-880	1.7	7
92	Development of Nickel Wire Bonding for High-Temperature Packaging of SiC Devices. <i>IEEE Transactions on Advanced Packaging</i> , <b>2009</b> , 32, 564-574		18
91	Electrically small folded slot antenna utilizing capacitive loaded slot lines <b>2008</b> ,		12
90	Determination of Young's moduli of 3C (110) single-crystal and (111) polycrystalline silicon carbide from operating frequencies. <i>Journal of Materials Science</i> , <b>2008</b> , 43, 4512-4517	4.3	7
89	Electric Field Patterning of Organic Nanoarchitectures with Self-Assembled Molecular Fibers. <i>Journal of Physical Chemistry C</i> , <b>2008</b> , 112, 12081-12084	3.8	11
88	RF MEMS switches with sic microbridges for improved reliability <b>2008</b> ,		9
87	Electrical Characterization of Microelectromechanical Silicon Carbide Resonators. <i>Sensors</i> , <b>2008</b> , 8, 5759-5774	5.8	8
86	Micro- and nanomechanical structures for silicon carbide MEMS and NEMS. <i>Physica Status Solidi (B): Basic Research</i> , <b>2008</b> , 245, 1404-1424	1.3	81
85	Amorphous SiC as a structural layer in microbridge-based RF MEMS switches for use in software-defined radio. <i>Solid-State Electronics</i> , <b>2008</b> , 52, 1647-1651	1.7	14
84	Mechanical properties of a 3C-SiC film between room temperature and 600 °C. <i>Journal Physics D: Applied Physics</i> , <b>2007</b> , 40, 3335-3342	3	29
83	Development of a Microfabricated Flat Interface Nerve Electrode Based on Liquid Crystal Polymer and Polynorbornene Multilayered Structures <b>2007</b> ,		5
82	Material Aspects of Micro- and Nanoelectromechanical Systems <b>2007</b> , 299-322		
81	Mid-infrared metamaterial based on perforated SiC membrane: engineering optical response using surface phonon polaritons. <i>Applied Physics A: Materials Science and Processing</i> , <b>2007</b> , 88, 605-609	2.6	27
80	Effects of biomedical sterilization processes on performance characteristics of MEMS pressure sensors. <i>Biomedical Microdevices</i> , <b>2007</b> , 9, 809-14	3.7	3

79	Energy Dissipation in Folded-Beam MEMS Resonators Made from Single Crystal and Polycrystalline 3C-SiC Films <b>2007</b> ,		2
78	Electrostatically Driven Touch-Mode Poly-SiC Microspeaker <b>2007</b> ,		7
77	Low Temperature A-SiC/Si Direct Bonding Technology for MEMS/NEMS <b>2007</b> ,		3
76	A Polynorbornene-Based Microelectrode Array for Neural Interfacing <b>2007</b> ,		1
75	PECVD Silicon Carbide as a Thin Film Packaging Material for Microfabricated Neural Electrodes. <i>Materials Research Society Symposia Proceedings</i> , <b>2007</b> , 1009, 1		3
74	Development of amorphous SiC for MEMS-based microbridges <b>2007</b> ,		2
73	Characterization of frequency tuning using focused ion beam platinum deposition. <i>Journal of Micromechanics and Microengineering</i> , <b>2007</b> , 17, 213-219	2	34
72	Fabrication of hall device structures in 3C-SiC using microelectromechanical processing technology. <i>Microelectronic Engineering</i> , <b>2006</b> , 83, 1396-1399	2.5	3
71	Novel Polycrystalline SiC Films Containing Nanoscale Through-Pores by Selective APCVD. <i>Materials Science Forum</i> , <b>2006</b> , 527-529, 755-758	0.4	
70	Nitrogen-Doping of Polycrystalline 3C-SiC Films Deposited by Low Pressure Chemical Vapor Deposition. <i>Materials Science Forum</i> , <b>2006</b> , 527-529, 311-314	0.4	3
69	Fabrication and Characterization of Flexible, Microfabricated Neural Electrode Arrays Made from Liquid Crystal Polymer and Polynorbornene. <i>Materials Research Society Symposia Proceedings</i> , <b>2006</b> , 926, 1		5
68	Characterization of Low Stress, Undoped LPCVD Polycrystalline SiC Films for MEMS Applications. <i>Materials Science Forum</i> , <b>2006</b> , 527-529, 1103-1106	0.4	
67	PECVD Silicon Carbide as a Chemically-Resistant Thin Film Packaging Technology for Microfabricated Antennas <b>2006</b> ,		5
66	Development of PECVD SiC for MEMS Using 3MS as the Precursor. <i>Materials Research Society Symposia Proceedings</i> , <b>2006</b> , 911, 28		5
65	The mechanical properties of polycrystalline 3C-SiC films grown on polysilicon substrates by atmospheric pressure chemical-vapor deposition. <i>Journal of Applied Physics</i> , <b>2006</b> , 99, 044108	2.5	32
64	Electrothermal tuning of AlSiC nanomechanical resonators. <i>Nanotechnology</i> , <b>2006</b> , 17, 1506-1511	3.4	88
63	Fabrication and testing of bulk micromachined silicon carbide piezoresistive pressure sensors for high temperature applications. <i>IEEE Sensors Journal</i> , <b>2006</b> , 6, 316-324	4	79
62	SiC cantilever resonators with electrothermal actuation. <i>Sensors and Actuators A: Physical</i> , <b>2006</b> , 128, 376-386	3.9	50



61	DEPOSITION TECHNIQUES FOR SIC MEMS <b>2006</b> , 18-45		1
60	An oversampled capacitance-to-voltage converter IC with application to time-domain characterization of MEMS resonators. <i>IEEE Sensors Journal</i> , <b>2005</b> , 5, 1353-1361	4	15
59	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part I: growth study and device fabrication. <i>Journal of Microelectromechanical Systems</i> , <b>2005</b> , 14, 567-578	2.5	12
58	Polycrystalline 3C-SiC thin films deposited by dual precursor LPCVD for MEMS applications. <i>Sensors and Actuators A: Physical</i> , <b>2005</b> , 119, 169-176	3.9	42
57	Measurement of residual stress and elastic modulus of polycrystalline 3C-SiC films deposited by low-pressure chemical vapor deposition. <i>Thin Solid Films</i> , <b>2005</b> , 492, 195-202	2.2	37
56	Far-field detection of the super-lensing effect in the mid-infrared: theory and experiment. <i>Journal of Modern Optics</i> , <b>2005</b> , 52, 2351-2364	1.1	4
55	Polycrystalline silicon-carbide surface-micromachined vertical resonators-part II: electrical testing and material property extraction. <i>Journal of Microelectromechanical Systems</i> , <b>2005</b> , 14, 579-589	2.5	18
54	Mechanical properties of epitaxial 3C silicon carbide thin films. <i>Journal of Microelectromechanical Systems</i> , <b>2005</b> , 14, 664-672	2.5	40
53	Use of deposition pressure to control residual stress in polycrystalline SiC films. <i>Applied Physics Letters</i> , <b>2004</b> , 84, 341-343	3.4	45
52	Young's Modulus and Residual Stress of Polycrystalline 3C-SiC Films Grown by LPCVD and Measured by the Load-Deflection Technique. <i>Materials Science Forum</i> , <b>2004</b> , 457-460, 1519-1522	0.4	4
51	Characterization of Polycrystalline SiC Thin Films for MEMS Applications using Surface Micromachined Devices. <i>Materials Science Forum</i> , <b>2004</b> , 457-460, 1523-1526	0.4	5
50	Advanced Processing Techniques for Silicon Carbide MEMS and NEMS. <i>Materials Science Forum</i> , <b>2004</b> , 457-460, 1451-1456	0.4	4
49	Fabrication of Suspended Nanomechanical Structures from Bulk 6H-SiC Substrates. <i>Materials Science Forum</i> , <b>2004</b> , 457-460, 1531-1536	0.4	11
48	Surface Roughness Control of 3C-SiC Films during the Epitaxial Growth Process. <i>Journal of the Electrochemical Society</i> , <b>2004</b> , 151, G910	3.9	9
47	High-temperature single-crystal 3C-SiC capacitive pressure sensor. <i>IEEE Sensors Journal</i> , <b>2004</b> , 4, 464-470		157
46	Silicon carbide micro- and nanoelectromechanical systems <b>2004</b> ,		1
45	Femtosecond pulsed laser micromachining of single crystalline 3C-SiC structures based on a laser-induced defect-activation process. <i>Journal of Micromechanics and Microengineering</i> , <b>2003</b> , 13, 680-685	2.85	39
44	Nanoelectromechanical systems: Nanodevice motion at microwave frequencies. <i>Nature</i> , <b>2003</b> , 421, 496	50.4	438



43	Examination of Bulge Test for Determining Residual Stress, Young's Modulus, and Poisson's Ratio of 3C-SiC Thin Films. <i>Journal of Aerospace Engineering</i> , <b>2003</b> , 16, 46-54	1.4	65
42	Mechanical Properties and Morphology of Polycrystalline 3C-SiC Films Deposited on Si and SiO <sub>2</sub> by LPCVD. <i>Materials Research Society Symposia Proceedings</i> , <b>2003</b> , 795, 140		0
41	. <i>IEEE Transactions on Electron Devices</i> , <b>2002</b> , 49, 2323-2332	2.9	49
40	Evaluation of MEMS materials of construction for implantable medical devices. <i>Biomaterials</i> , <b>2002</b> , 23, 2737-50	15.6	361
39	Origin of the split Si-H stretch mode on hydrogen terminated 6H-SiC(0001): Titration of crystal truncation. <i>Applied Physics Letters</i> , <b>2002</b> , 80, 4726-4728	3.4	22
38	Quantitative evaluation of biaxial strain in epitaxial 3C-SiC layers on Si(100) substrates by Raman spectroscopy. <i>Journal of Applied Physics</i> , <b>2002</b> , 91, 1113-1117	2.5	71
37	High-energy femtosecond pulsed laser micromachining of thin film deposited silicon in self-focused air medium. <i>Journal of Laser Applications</i> , <b>2002</b> , 14, 221-229	2.1	4
36	Deposition of Polycrystalline 3C-SiC Films on 100 mm Diameter Si(100) Wafers in a Large-Volume LPCVD Furnace. <i>Electrochemical and Solid-State Letters</i> , <b>2002</b> , 5, G99		57
35	Chemical Mechanical Polishing of Cubic Silicon Carbide Films Grown on Si(100) Wafers. <i>Journal of the Electrochemical Society</i> , <b>2002</b> , 149, G643	3.9	11
34	Development of a Multilayer SiC Surface Micromachining Process with Capabilities and Design Rules Comparable to Conventional Polysilicon Surface Micromachining. <i>Materials Science Forum</i> , <b>2002</b> , 389-393, 755-758	0.4	17
33	Pendeo-epitaxial growth of thin films of gallium nitride and related materials and their characterization. <i>Journal of Crystal Growth</i> , <b>2001</b> , 225, 134-140	1.6	56
32	Conventional and pendeo-epitaxial growth of GaN(0001) thin films on Si(111) substrates. <i>Journal of Crystal Growth</i> , <b>2001</b> , 231, 335-341	1.6	32
31	Surface Micromachining: A Brief Introduction. <i>MRS Bulletin</i> , <b>2001</b> , 26, 289-290	3.2	7
30	On the stability of $\beta$ -SiC with respect to chemical disorder induced by irradiation with energetic particles. <i>Philosophical Magazine Letters</i> , <b>2001</b> , 81, 55-61	1	4
29	Monocrystalline silicon carbide nanoelectromechanical systems. <i>Applied Physics Letters</i> , <b>2001</b> , 78, 162-164	3.4	223
28	A Novel Method of Fabricating SiC-On-Insulator Substrates for Use in MEMS. <i>Materials Research Society Symposia Proceedings</i> , <b>2001</b> , 681, 1		
27	Pendeo-epitaxial growth of gallium nitride on silicon substrates. <i>Journal of Electronic Materials</i> , <b>2000</b> , 29, 306-310	1.9	19
26	Silicon carbide for microelectromechanical systems. <i>International Materials Reviews</i> , <b>2000</b> , 45, 85-108	16.1	113

25	. <i>Journal of Physics Condensed Matter</i> , <b>2000</b> , 12, 10175-10183	1.8	12
24	Fabrication and testing of surface micromachined polycrystalline SiC micromotors. <i>IEEE Electron Device Letters</i> , <b>2000</b> , 21, 164-166	4.4	49
23	Roughness Reduction of 3C-SiC Surfaces Using SiC-Based Mechanical Polishing Slurries. <i>Journal of the Electrochemical Society</i> , <b>1999</b> , 146, 327-330	3.9	16
22	Growth of polycrystalline SiC films on SiO <sub>2</sub> and Si <sub>3</sub> N <sub>4</sub> by APCVD. <i>Thin Solid Films</i> , <b>1999</b> , 355-356, 179-183	1.8	6
21	SiC MEMS: opportunities and challenges for applications in harsh environments. <i>Thin Solid Films</i> , <b>1999</b> , 355-356, 518-524	2.2	219
20	Fabrication and testing of micromachined silicon carbide and nickel fuel atomizers for gas turbine engines. <i>Journal of Microelectromechanical Systems</i> , <b>1999</b> , 8, 251-257	2.5	57
19	Surface micromachining of polycrystalline SiC films using microfabricated molds of SiO <sub>2</sub> /sub 2/ and polysilicon. <i>Journal of Microelectromechanical Systems</i> , <b>1999</b> , 8, 237-242	2.5	37
18	Fabrication of low defect density 3C-SiC on SiO <sub>2</sub> structures using wafer bonding techniques. <i>Journal of Electronic Materials</i> , <b>1998</b> , 27, L17-L20	1.9	19
17	Performance of 3C-SiC thin films as protective coatings for silicon-micromachined atomizers. <i>Thin Solid Films</i> , <b>1998</b> , 315, 170-178	2.2	19
16	Silicon carbide MEMS for harsh environments. <i>Proceedings of the IEEE</i> , <b>1998</b> , 86, 1594-1609	14.3	320
15	Spatial Uniformity of the Mechanical Properties of 3C-SiC Films Grown on 4-Inch Si Wafers as a Function of Film Growth Conditions. <i>Materials Science Forum</i> , <b>1998</b> , 264-268, 635-640	0.4	2
14	Behaviour of Polycrystalline SiC and Si Surface-Micromachined Lateral Resonant Structures at Elevated Temperatures. <i>Materials Science Forum</i> , <b>1998</b> , 264-268, 889-894	0.4	6
13	Characterization of polycrystalline silicon carbide films grown by atmospheric pressure chemical vapor deposition on polycrystalline silicon. <i>Journal of Materials Research</i> , <b>1998</b> , 13, 406-412	2.5	43
12	Surface Micromachining of Polycrystalline SiC Deposited on SiO <sub>2</sub> by APCVD. <i>Materials Science Forum</i> , <b>1998</b> , 264-268, 885-888	0.4	27
11	Etching of 3C-SiC using CHF <sub>3</sub> /O <sub>2</sub> and CHF <sub>3</sub> /O <sub>2</sub> /He plasmas at 1.75 Torr. <i>Journal of Vacuum Science &amp; Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena</i> , <b>1998</b> , 16, 536		23
10	Finite-Element Modeling of Residual Stress in SiC Diaphragms. <i>Materials Research Society Symposia Proceedings</i> , <b>1998</b> , 518, 221		1
9	Micro/Nanotribological Studies of Single-Crystal Silicon and Polysilicon and SiC Films for Use in MEMS Devices <b>1998</b> , 407-430		21
8	New developments in MEMS using SiC and TiNi shape memory alloy materials. <i>Current Opinion in Solid State and Materials Science</i> , <b>1997</b> , 2, 566-570	12	3

7	Stable secondary electron emission from chemical vapor deposited diamond films coated with alkali-halides. <i>Applied Physics Letters</i> , <b>1995</b> , 66, 242-244	3-4	30
6	Epitaxial growth of 3CβC films on 4 in. diam (100) silicon wafers by atmospheric pressure chemical vapor deposition. <i>Journal of Applied Physics</i> , <b>1995</b> , 78, 5136-5138	2-5	206
5	Deep level defects and carrier removal due to proton and alpha particle irradiation of InP. <i>Journal of Applied Physics</i> , <b>1994</b> , 75, 3187-3189	2-5	13
4	Stable secondary electron emission observations from chemical vapor deposited diamond. <i>Applied Physics Letters</i> , <b>1994</b> , 65, 2702-2704	3-4	33
3	Composition and physical properties of thin a-C:N and a-C:N:H films deposited by ion beam techniques. <i>Surface and Interface Analysis</i> , <b>1994</b> , 21, 95-100	1-5	5
2	Synthesis and Characterization of Nitrogen Containing Diamondlike Carbon Films made by ion Beam Deposition. <i>Materials Research Society Symposia Proceedings</i> , <b>1994</b> , 349, 465		5
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